White-Light Interferometer
Bruker NPFLEX-LA

Description:
- The optical measuring device enables a quantitative evaluation of surfaces
- The surface is illuminated with focused white light, which is superposed with a reference beam path to create interference patterns
- The surface topography is calculated from the intensity profile in Z direction
- The measuring device is characterized by a high measuring speed

Technical Specifications:
- Resolution in z-direction: 0.15 nm
- Lateral resolution: max. 0.20 nm
- Measurement principle: White-Light Interferometry
- Rotation feed: Ideal for cylindrical surfaces

Field of Application:
- Standardized determination of surface parameters according to DIN EN ISO 4287/4288 possible
- A rotation unit allows the measurement of twist structures on shaft surfaces
- Measurement of distances, depths, volumes and geometries
- Damage analysis: scratches, defects, etc.
- Wear measurements, running track wear of an RSS on a shaft, etc.